

Please amend the original Abstract at page 19, lines 1-8, as follows:

ABSTRACT

Provided is a method of producing an alumina film mainly in $[\alpha]$ alpha crystal structure superior in heat resistance, wherein the alumina film mainly in $[\alpha]$ alpha crystal structure is formed on a substrate, independently of the kind of the substrate at relatively low temperature, by treating the substrate surface with a ceramic powder mainly having the crystal structure same as that of alumina in the $[\alpha]$ alpha crystal structure, in forming the alumina film mainly in $[\alpha]$ alpha crystal structure on the substrate (including the substrate having a film previously formed thereon).